



UNITED STATES PATENT and TRADEMARK OFFICE

UNDER SECRETARY OF COMMERCE FOR INTELLECTUAL PROPERTY AND
DIRECTOR OF THE UNITED STATES PATENT AND TRADEMARK OFFICE
WASHINGTON, D.C. 20231
WWW.USPTO.GOV

MAY 12 2004

In re Application of	:	
Choi, Chul-Hwan et al	:	NOTICE OF WITHDRAWAL
Serial No. 10/046282	:	FROM ISSUE
Filed: January 16, 2002	:	UNDER 37 CFR 1.313
For: RESIDUAL GAS REMOVING DEVICE	:	
AND METHOD THEREOF	:	

The above-identified application is withdrawn from issue after payment of the issue fee due to reopening of prosecution. See 37 CFR 1.313. (b).

The above-identified application is hereby withdrawn from issue to permit reopening. An office action from the examiner will follow in due course.

The issue fee is refundable upon written request. If, however, the application is again found allowable, the issue fee can be applied toward payment of the issue fee in the amount identified on the new Notice of Allowance and Issue Fee Due upon written request. This request and any balance due must be received on or before the due date noted in the new Notice of Allowance in order to prevent abandonment of the application.

Telephone inquiries should be directed to Blaine Copenheaver at (571) 272-1156.

The above-identified application is being forwarded to the examiner for prompt appropriate action, including notifying applicant of the new status of this application.

Jacqueline Stone, Director
Technology Center 1700
Chemical and Materials Engineering

VOLENTINE FRANCOS, P.L.L.C.
Suite 150
12200 Sunrise Valley Drive
Reston VA 20191

CC: Allowed Files